

**Abstract**

5       An objective lens with magnetic and electrostatic focusing for an electron microscopy  
system is provided whose at least partially conical outer shape allows orienting an object  
to be imaged at a large angle range in respect of an electron beam, said objective lens  
exhibiting, at the same time, good optical parameters. This is enabled by a specific  
geometry of the lens elements. Furthermore, an examination for the simultaneous  
10       imaging and processing of an object is proposed which comprises, besides an electron  
microscopy system with the above-mentioned objective lens, also an ion beam processing  
system and an object support.

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